

ABSTRACT OF THE DISCLOSURE

The apparatus for inspecting a substrate of the present invention comprises substrate holding member for holding a substrate to be inspected, a driving
5 mechanism for raising the substrate holding member to a predetermined angle or less, a position coordinate detecting section provided at side edge of the substrate in at least two directions, for detecting coordinates of a defect present in the substrate,
10 an observation system supporting section provided for supporting a micro observation system and moving on the surface of the substrate, and a controlling section for controlling of the movement of the micro observation system of the observation system supporting section to
15 correspond to a defect present in the substrate, on the basis of the position coordinates of the defect detected by the position coordinate detecting section.